ElectriTap300-G

AFM Tip

SHAPE	HEIGHT	SETBACK	RADIUS	HALF CONE ANGLE
Rotated	17 µm (15 – 19 µm)*	15 µm (10 – 20 µm)*	25 nm	20°–25° along cantilever axis, 25°–30° from side, 10° at the apex

AFM Cantilever

Cantilever A	
Shape	Beam
Force Constant	40 N/m (20 – 75 N/m)*
Resonance Frequency	300 kHz (200 – 400 kHz)*
Length	125 µm (115 – 135 µm)*
Width	30 µm (25 – 35 µm)*
Thickness	4 µm (3 – 5 µm)*

* typical range

Coating

Electrically conductive coating of 5 nm Chromium and 25 nm Platinum on both sides of the cantilever. This coating also enhances the laser reflectivity of the cantilever.

Alignment Grooves

This product features alignment grooves on the back side of the holder chip.

Additional Info

Monolithic silicon AFM probe for high frequency non-contact and tapping mode operation, and electric modes such as:

— scanning capacitance microscopy (SCM)
— electrostatic force microscopy (EFM)
— Kelvin probe force microscopy (KFM)
— scanning probe lithography

The rotated AFM tip allows for more symmetric representation of high sample features. The consistent AFM tip radius ensures good resolution and reproducibility.

The AFM holder chip fits most commercial AFM systems as it is industry standard size.